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TOUCHSCREEN SERIES C

RECIPE CAPABLE WITH PROCESS DATA REVIEW NEW !

• AWARD WINNING SOFTWARE EASILY CONTROLS ROBUST SERIES C HARDWARE

• THE SERIES C LIINE HAS PIONEERED RESULT REPRODUCIBILITY IN BOTH INDUSTRY AND FACILITIES WORLDWIDE

STAND ALONE MODELS FOR 4", 6" AND 8" WAFERS

- • PROCESS DATA REVIEW
- • INTEGRATED SOTER CONSDENSER
- • PROGRAMMABLE TOUCHSCREEN CONTROL
- • 0.08 μm MICRO-FILTERED LCO_2 DELIVERY TO PROCESS CHAMBER
- • DEDICATED SLOW FILL CREATES IDEAL FLUID DYNAMICS FOR MORE SENSITIVE DEVICES
- • SUBSTRATE PROCESS FLEXIBILITY FOR WAFER PIECES, VARIOUS SIZES OF DIE, AND WAFERS UP TO 8"
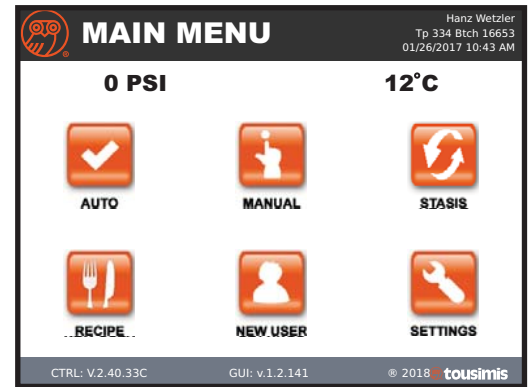
MADE IN U.S.A.

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Touch Screen Series C Model Choices
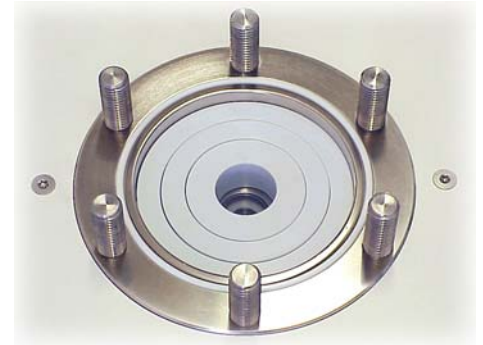*Various Chamber sizes Available for up to 8 inch Wafers*

4" Wafer - *Autosamdri®-934, Series C* (Cat.# 8788A)
6" Wafer - *Automegasamdri®-936, Series C* (Cat.# 8788B)
8" Wafer - *Automegasamdri®-938, Series C* (Cat.# 8788C)

MAIN MENU
Hanz Wetzler
Tp 334 Btch 16653
01/26/2017 10:43 AM

0 PSI   12°C

AUTO   MANUAL   STASIS

RECIPE   NEW USER   SETTINGS

CTRL: V.2.40.33C   GUI: v.1.2.141   ® 2018 tousimis

Touch Screen Main Menu View

FEATURES

- Simple LCD Touch Screen Control
- Previous Run Data Review
- Use Factory Default Automatic Settings or Create Your Own Custom Recipes
- "Stasis Software" (Patent Pending) for versatile sample types
- Process up to 5 wafers per process run with each system
- HF Compatible Wafer Holders and 10mm Square Die Holder included with each system
- Tousimis® HF compatible Wafer Holders* may be used to wet etch and process your wafers minimizing handling
- Unique Chamber Inserts* easily reduce chamber ID decreasing LCO_2 consumption
- Closed loop cooling system cuts LCO_2 consumption by 50%
- "Vortex Swirl" non-mechanical Purge Mode Stirring (Patent Pending) eliminates the need for moving parts eliminating the need for future maintenance
- Static pressure control module helps ensure pressure safety
- Internal filtration system delivers clean LCO_2 into process chamber down to 0.08µm
- New 'Slow Fill' Control for the most delicate Sample Types
- LCO_2 flow is controlled through Micro Metering Valves with Vernier handles for precise flow control and easy position setting readjustment
- Chamber illumination with view port facilitates chamber status visualization*
- All internal surfaces are inert to CO_2, Acetone and Ultrapure Alcohols
- Cleanroom static-free compatible design
- External mounted Post Purge Filter Assembly for EZ preventive maintenance maintenance*
- The patented internal SOTER™ Condenser* quietly captures and separates CO_2 exhaust and waste alcohol
- All electronic components meet CE, UL and/or U.S. Military Specifications

4" Process Chamber with Chamber Inserts

SPECIFICATIONS

- Cabinet: 19.8" (50.3cm) Width x 31.7" (80.6cm) Depth x 44.5" (113.0cm) Height
- System Set-Up Area Footprint: 27" (68.6cm) Width x 38" (96.5cm) Depth x 44.5" (113cm) Height
- 120V or 220V / 50-60Hz systems available

STANDARD ACCESSORIES

- LCO_2 High Pressure braided stainless steel Teflon® lined hose, 10ft (3m). (Other lengths available upon request)
- Double T-Filter Assembly (Cat.# 8785) pre-installed onto the High Pressure hose. Filters LCO_2 twice down to 0.5µm with 99.5% particulate retention prior to LCO_2 entering system
- Tool Set included for making all basic start-up connections
- Static free exhaust tubing provided for all exhaust outlets
- Spare Chamber O-Rings (3), Backing Ring (1), Chamber Lamp (1) and Fuses
- Chamber Inserts* save LCO_2 by reducing Process Chamber size down to 1.25" ID
- HF Compatible Wafer Holder Set included with each system
- 2 year warranty on all parts and labor
- Free lifetime technical support
- Made in USA

HF Compatible Wafer Holder

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